ISC Audits & Reviews SC Summary (Nov 11th, 2025)

Doc.	Title	Vote
6592;	New Standard: Specification for Container for Transport and Storage of Transmission Electron Microscope (TEM) Lamella Carriers within Electron Microscopy Workflows;	Passed
6743C;	Revision to SEMI E95-1101, Specification for Human Interface for Semiconductor Manufacturing Equipment;	Passed
6906A;	New Standard: Terminology for Flexible Hybrid Electronics (FHE);	Passed
7242;	New Standard: Guide for Reliability of Flexible Hybrid Electronics;	Passed
7319-LI1;	To update website information where JEITA EM-3509 is available on footnote.;	Passed
7320;	Revision to SEMI M1-0924, Specification for Polished Single Crystal Silicon Wafers ;	Passed
7321B-LI1;	Add filtering capabilities and constraints for retrieving SEMI E125 metadata;	Passed
7321B-LI2;	Update issues raised by TF members;	Passed
7334-LI1;	To comply with SEMI Style Manual;	Passed
7346-LI1;	Replace Biased Terms;	Passed
7346-LI2;	Updates to References, Trademarks and Other Editorial Changes;	Passed
7354-LI1;	Improve technical issues found through 5 years review;	Passed
7354-LI2;	To comply with SEMI Regulations/Procedure Manual/Style Manual;	Passed
7354-LI3;	Revisit the definition of the term 'host' to use only one definition per the Style Manual;	Passed
7354-LI4;	Improve editorial issues;	Passed
7358;	Reapproval of SEMI D76-0318, Test Method for Viewing Angle Characteristic Using Reference Color on Visual Display;	Passed
7359;	Reapproval of SEMI G11-0519, Practice for RAM Follower Gel Time and Spiral Flow of Thermal Setting Molding Compounds;	Passed
7360;	Reapproval of SEMI G73-0519, Test Method for Pull Strength for Wire Bonding;	Passed
7361;	Reapproval of SEMI G77-0699 (Reapproved 1020), Specification for Frame Cassette for 300 mm Wafers;	Passed
7367;	New Auxiliary Document: Using Machine Learning Image Processing Algorithms to Characterize Multimodal Particle Size Distributions of Chemical Mechanical Planarization Slurries;	Passed
7368;	Reapproval of SEMI 3D12-1020, Guide for Measuring Flatness and Shape of Low Stiffness Wafers;	Passed
7371-LI1;	Addition, to §5, of a NOTE clarifying that, based on its definition and other criteria in this Safety Guideline, the specified widths of the exclusion zones are minima.;	Passed
7371-LI4;	Clarification of which material in the "Description and Comments" column is intended to be normative and which is intended to be informative, by formatting the latter as NOTEs. Addition of several	Passed

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	informative statements to that column. The items designated as NOTEs have alphabetic designators that will be changed to numbers, serially throughout the ballot, during publication. (five parts). ;	
7371-LI5;	(three parts): Addition, to several rows in Table A1-1 and Table A1-2, of NOTEs identifying symbols as having been developed by the S1 TF.;	Passed
7371-LI6;	Addition, to several rows in Table A1-1, of permission to represent different machine components, as well as the current permission to represent different body parts and orientations. Also, delete two claims that the symbols are from ANSI documents, as those claims appear to be incorrect.;	Passed
7371-LI9;	Restoration, to Table A1-1, of an alternative symbol for inhalation hazards.;	Passed
7371-LI10;	Addition, to Table A1-1, of a symbol analogous to the GHS symbol for "Health Hazard";	Passed
7374;	Revision to add a new Subordinate Standard: Specification For Panel FOUP Load Port With Ground Based Delivery Exclusion Volume to SEMI E182-0424 Specification For Panel Foup Loadport For Panel Level Packaging;	Passed
7375;	New Standard: Preliminary Specification for Large Tray Stack FOUP (LTSF);	Passed
7376-LI1;	Correct issues with SEMI E30 variables;	Passed
7377-LI1;	Correct issues with SEMI E40 variables;	Passed
7378-LI1;	Correct issues with SEMI E87 variables;	Passed
7378-LI2;	Correct issues with BypassScanSlotMap functionality;	Passed
7380-LI2;	Address issues raised by TF members;	Passed
R6601B;	Ratification Ballot - New Standard: Guide for Meeting IRDS Yield Table Recommendations for High Purity Polymer Materials and Components Used in Ultrapure Water;	Passed

For more information, please contact the SEMI Standards Engineer/Coordinator. (http://www.semi.org/standards/contacts) nearest you.

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